



Acoustic Emission & Printed Electronics

by

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Outline

- Acoustic Emission
 - Visual vs AE & X-ray vs AE
 - AE and X-ray of LGA and flip-chip CGAs
 - Microsection verification
 - Summary-AE
- Printed Electronics Technologies
 - PET definition, Mix of Technologies
 - PET vs Conventional
 - OE-A and iNEMI Roadmaps
 - Summary - PET



Visual Vs C-SAM

Visual Inspection

Excellent for exposed solder joints inspection including de-wetting, cold solder, contamination, stress marks

No inspection of hidden features, flip chip solder, underfill voids, delamination, FCGA/CGA

C-SAM Inspection

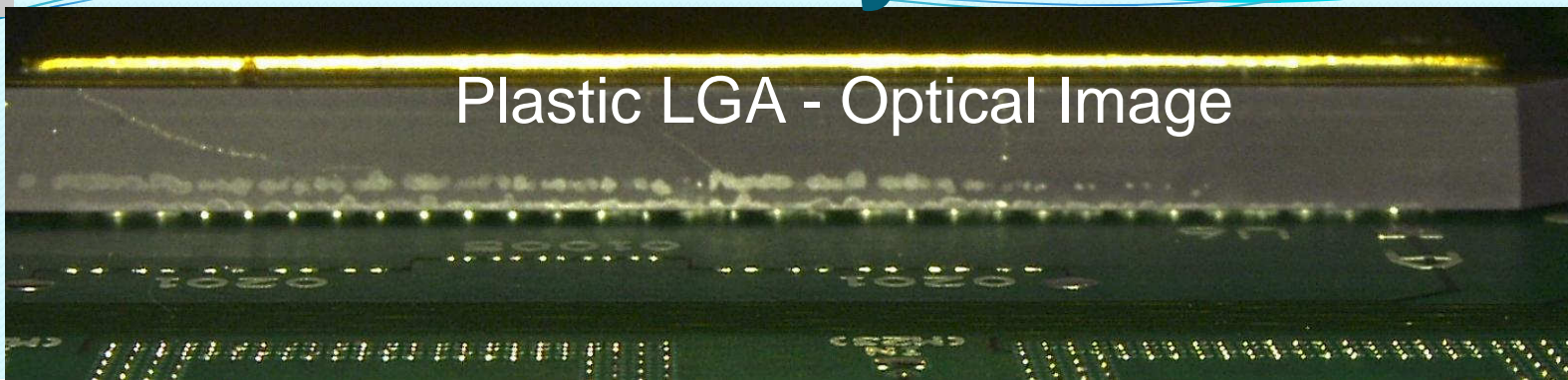
Excellent for hidden defects
Delamination/voids /crack

Cannot detect features when interference with AE signal

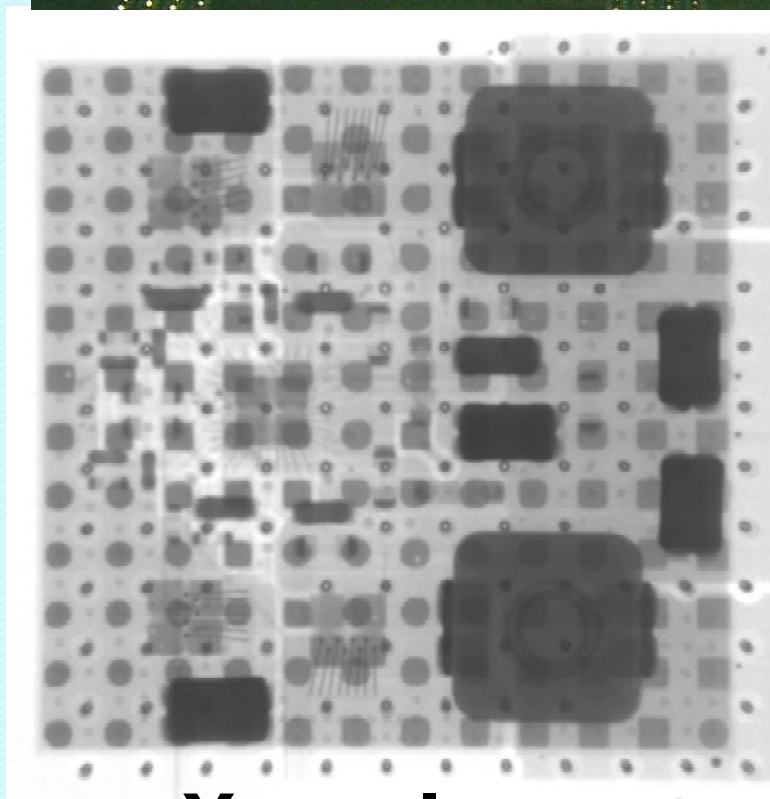
C-SAM needs to be inserted into water



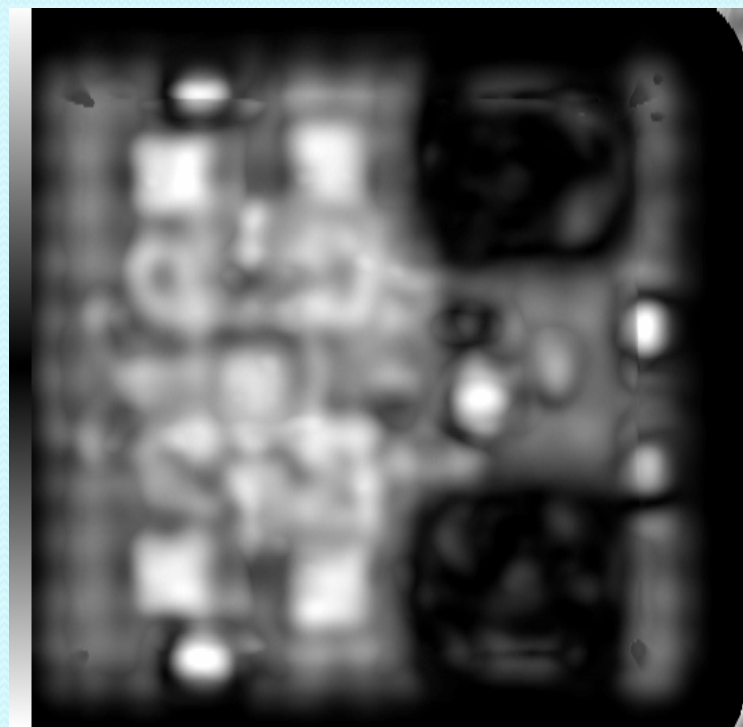
P-LGA X-ray/C-SAM



Plastic LGA - Optical Image



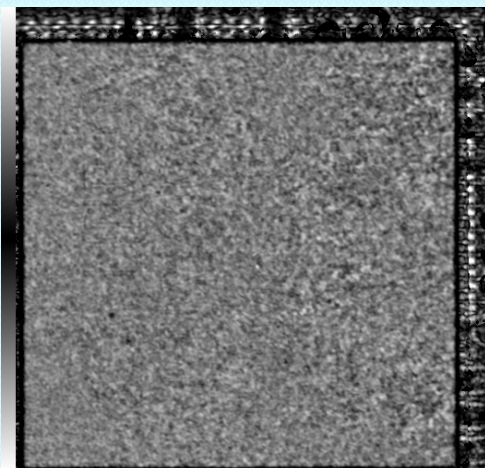
X-ray Image



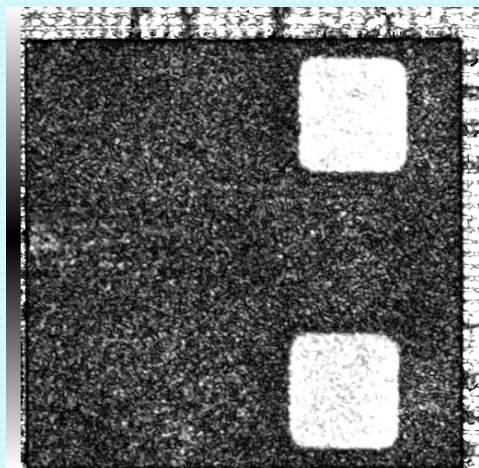
C-SAM Image- 5 MHz



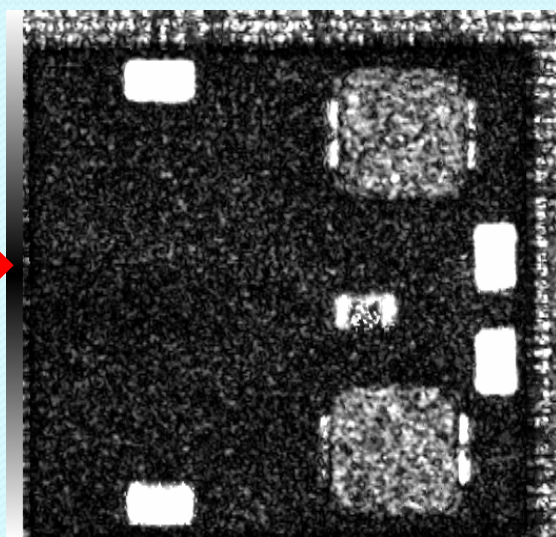
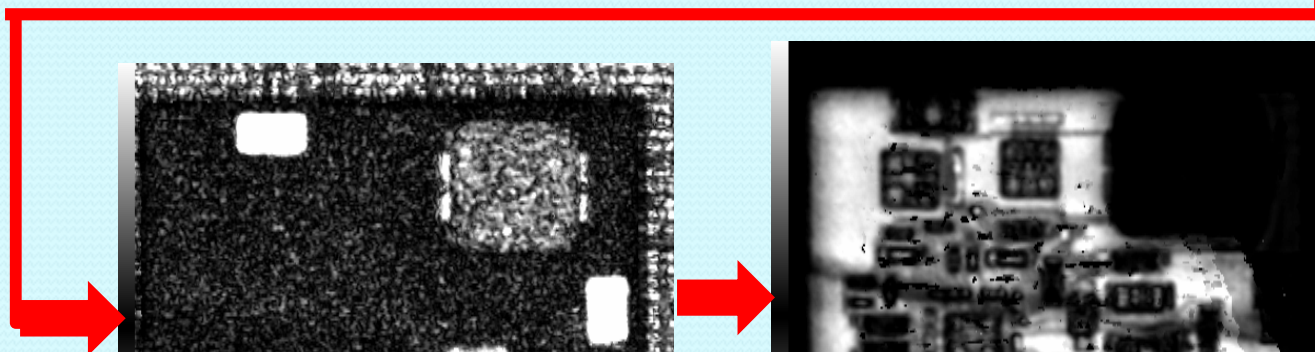
Layering C-SAM P-LGA



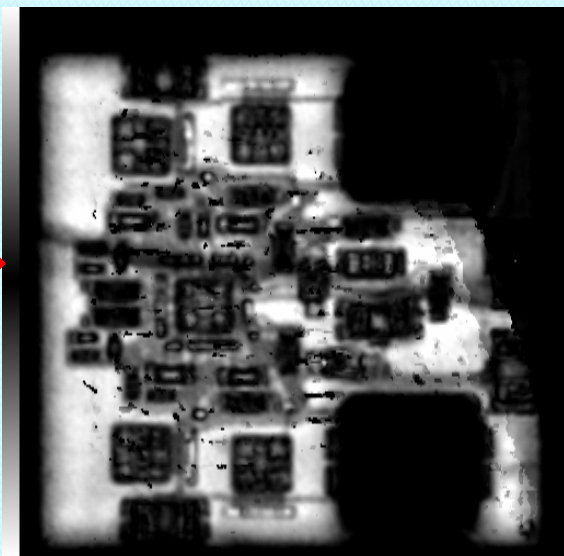
25 MHz -A TOP



25 MHz -B



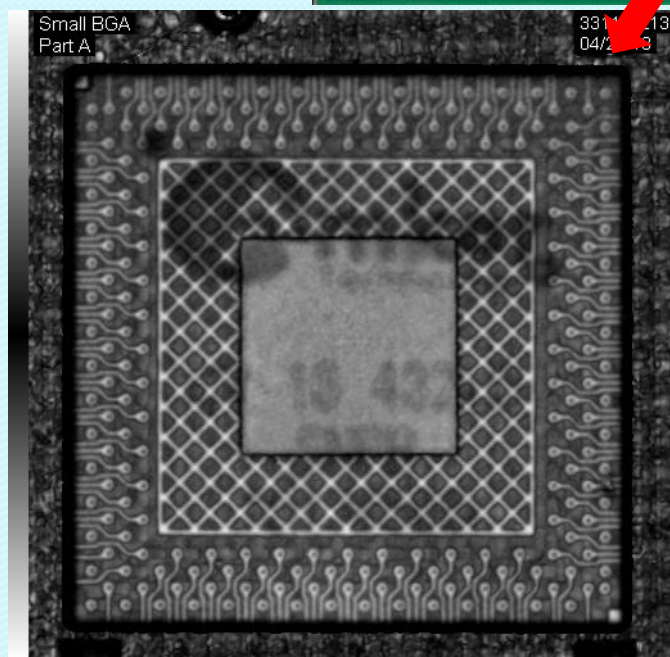
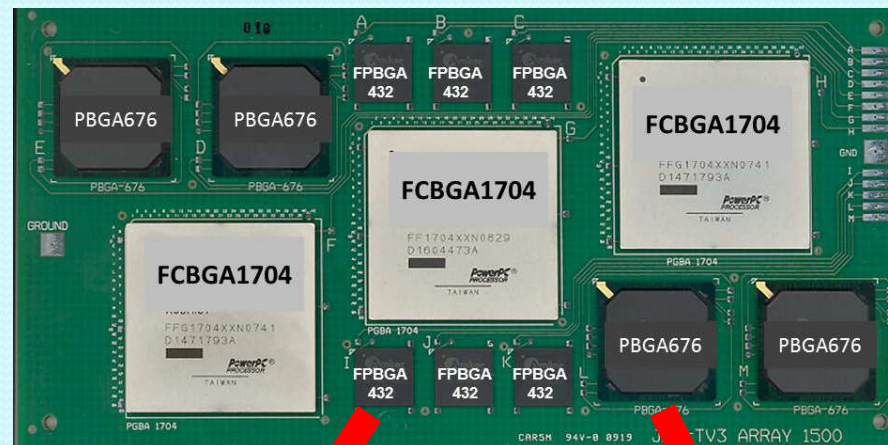
25 MHz -C



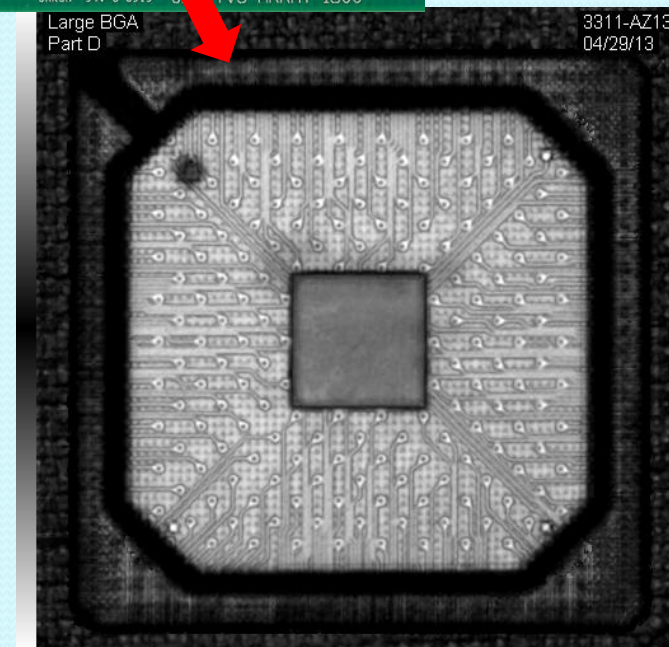
25 MHz -D



C-SAM PBGA Samples



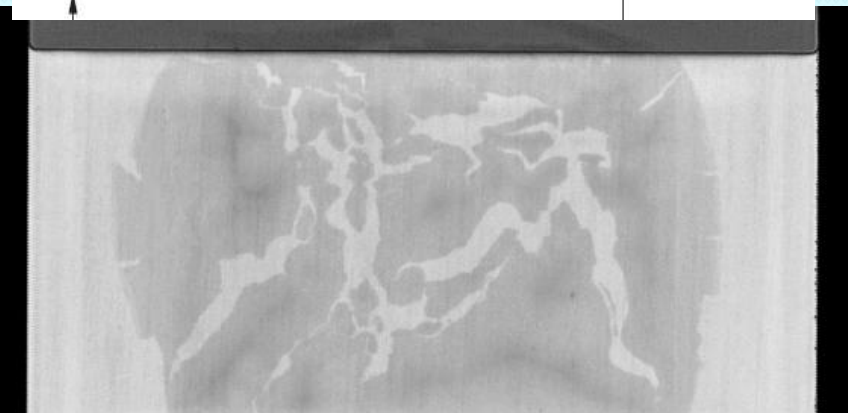
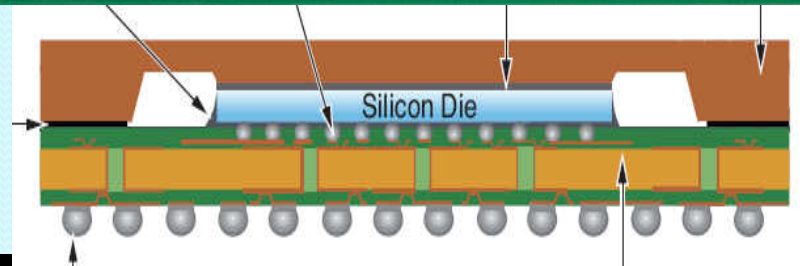
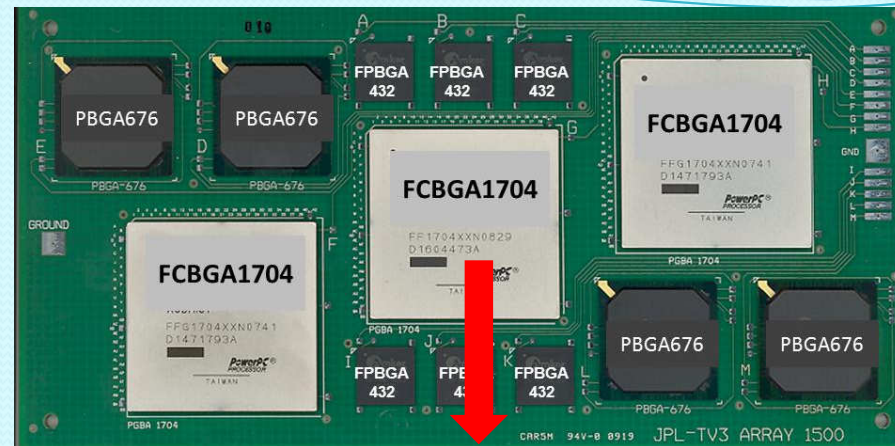
SN11 Part A- PBGA 432



SN11 Part D- PBGA 676



C-SAM FC-BGA

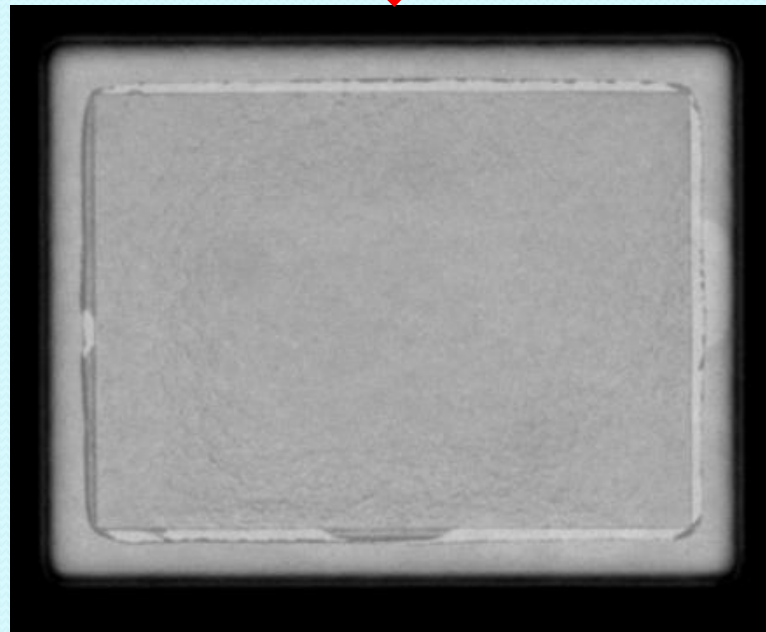
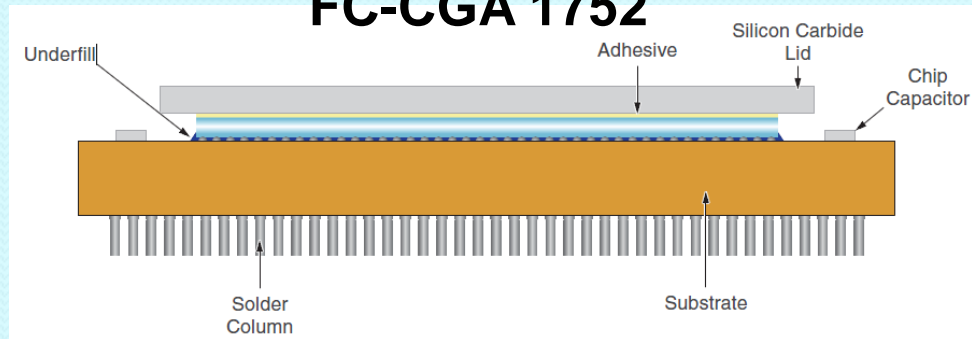


C-SAM Image-Heat Sink Interface



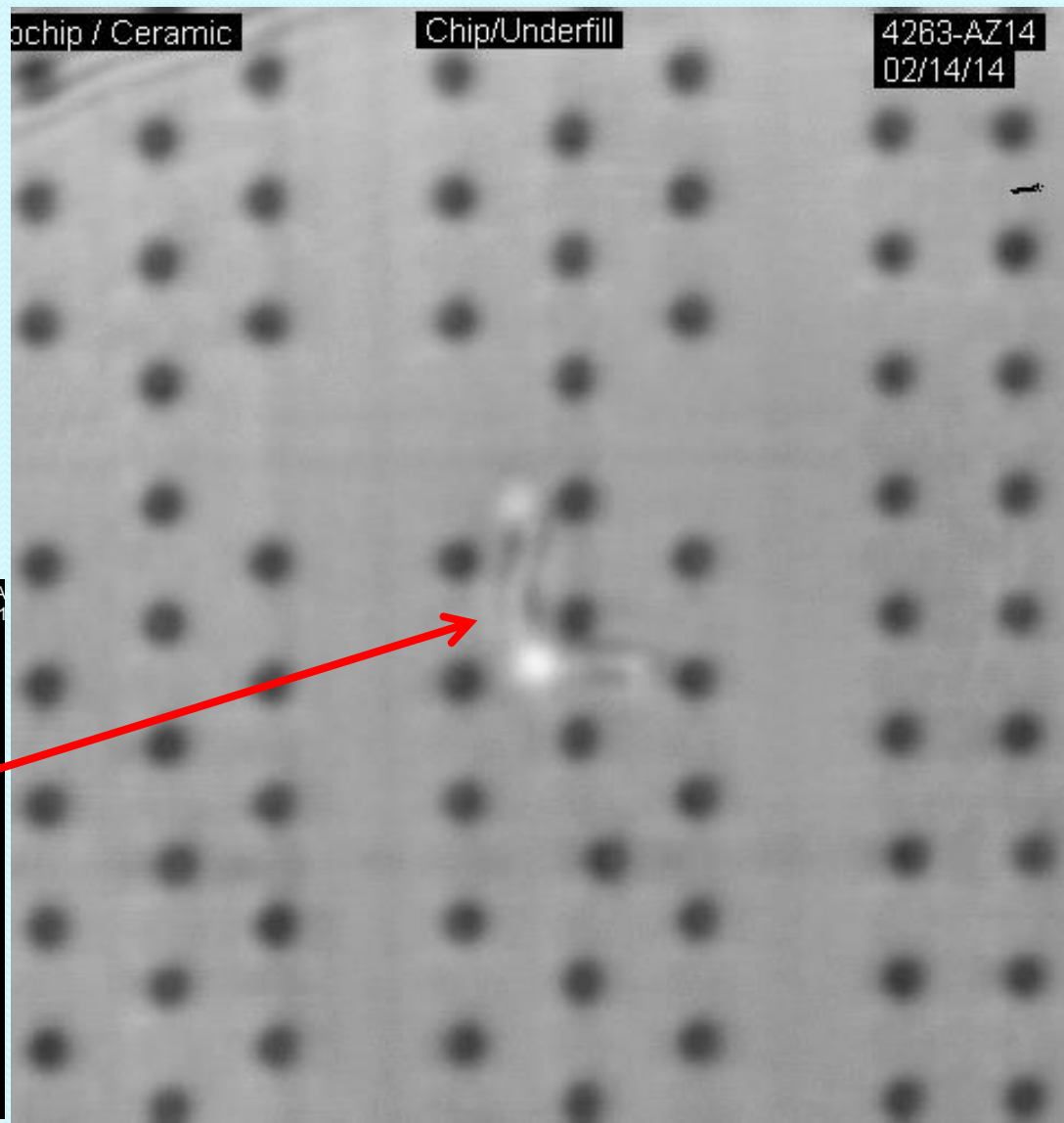
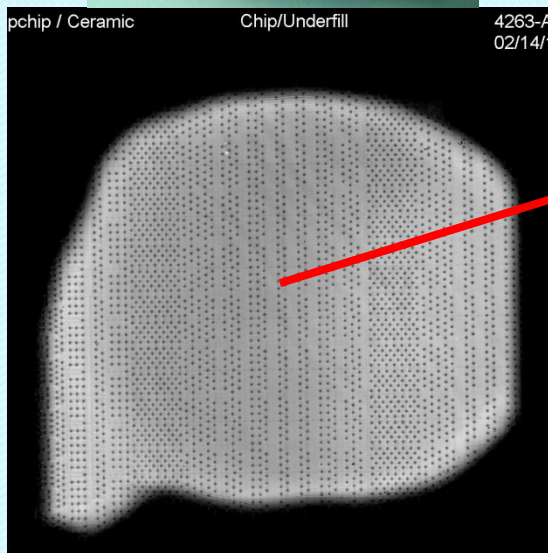
C-SAM FC-CGA

FC-CGA 1752



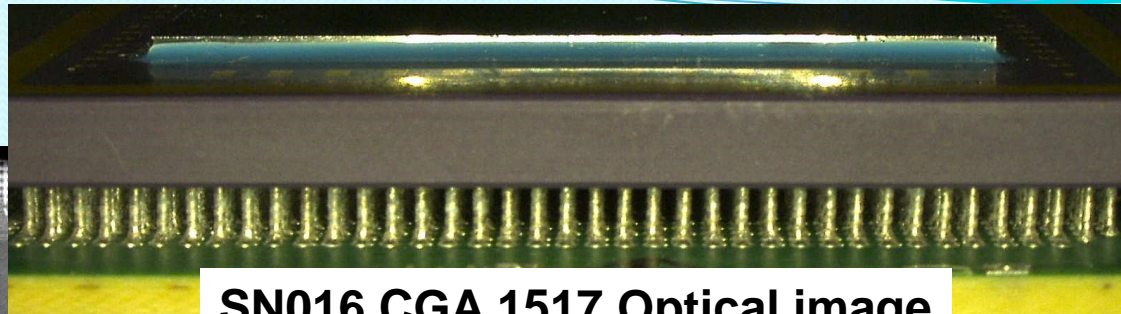


C-SAM FC-CGA

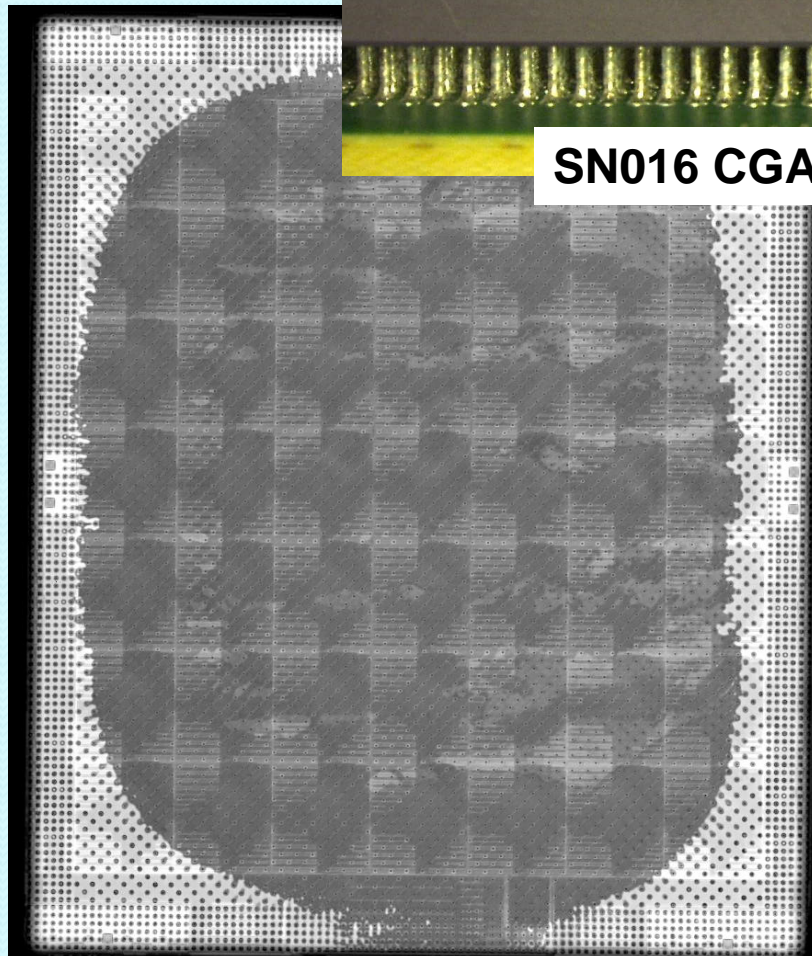




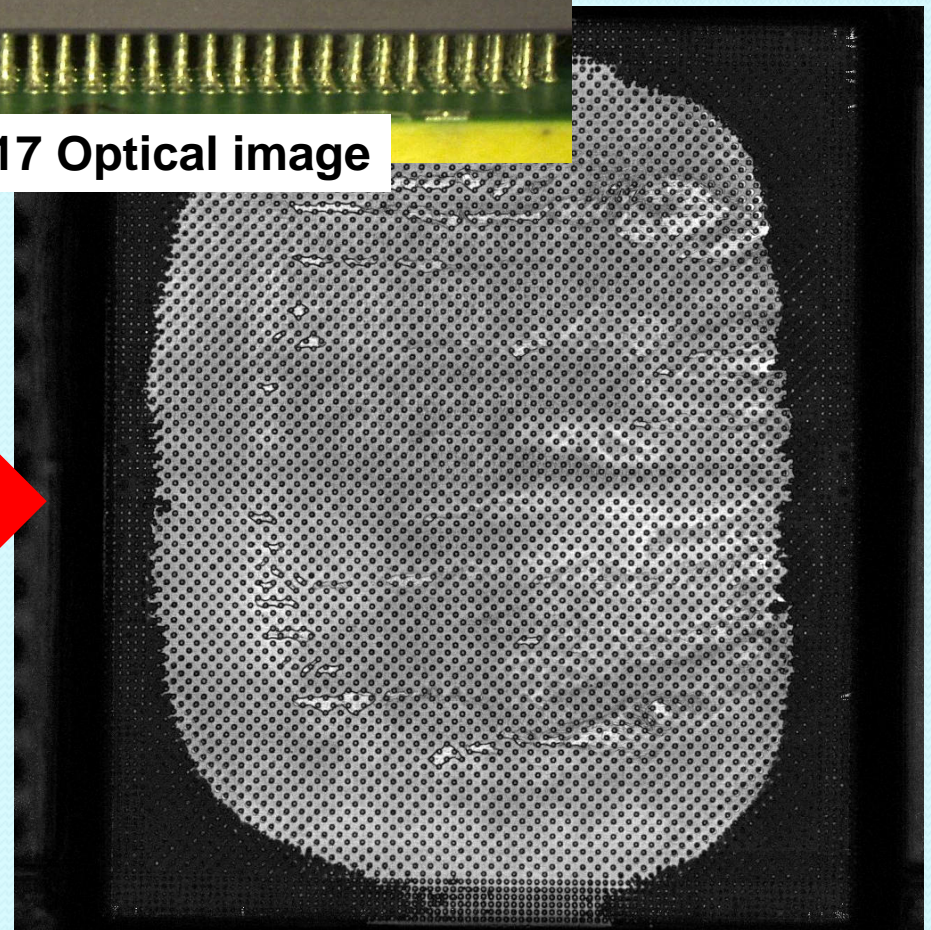
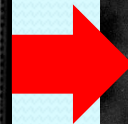
C-SAM FC-CGA



SN016 CGA 1517 Optical image



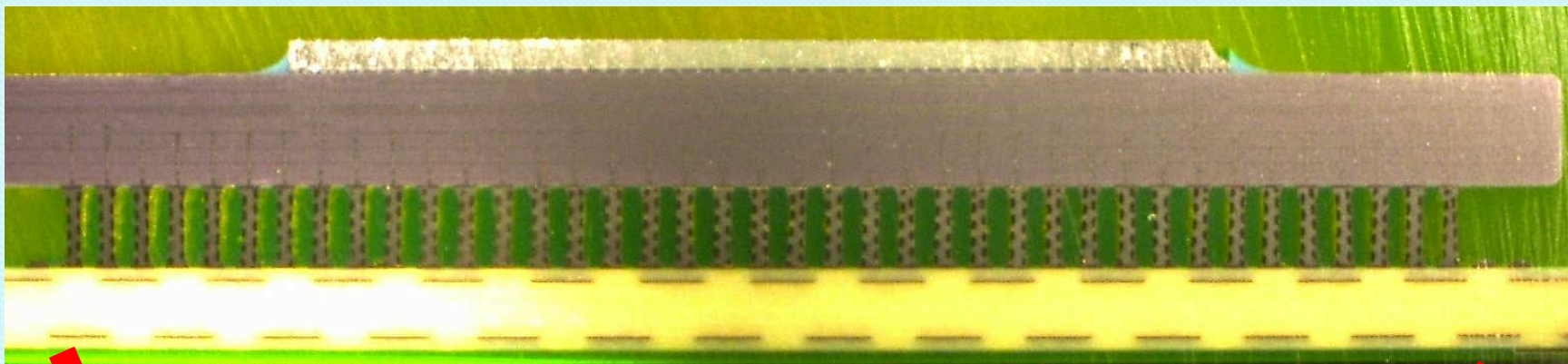
Flip-chip die interface
230 MHz



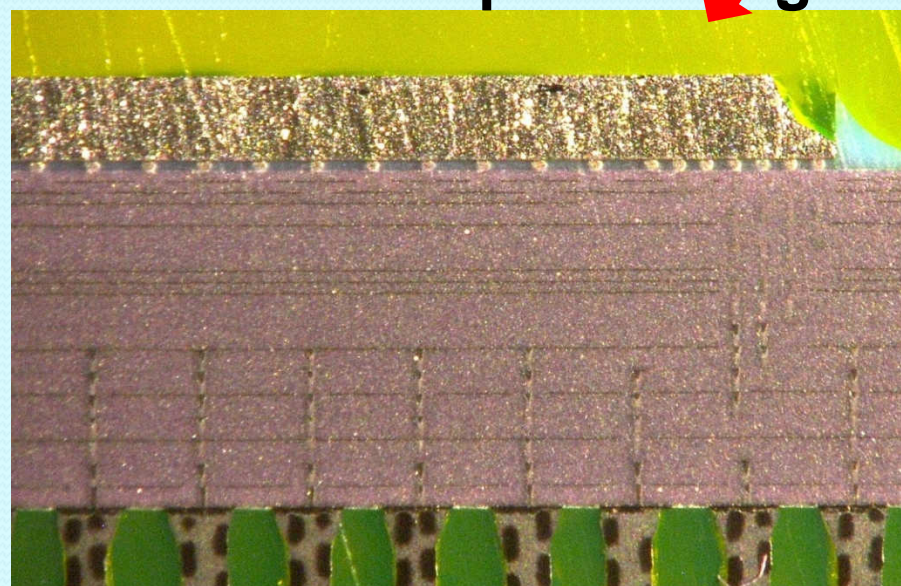
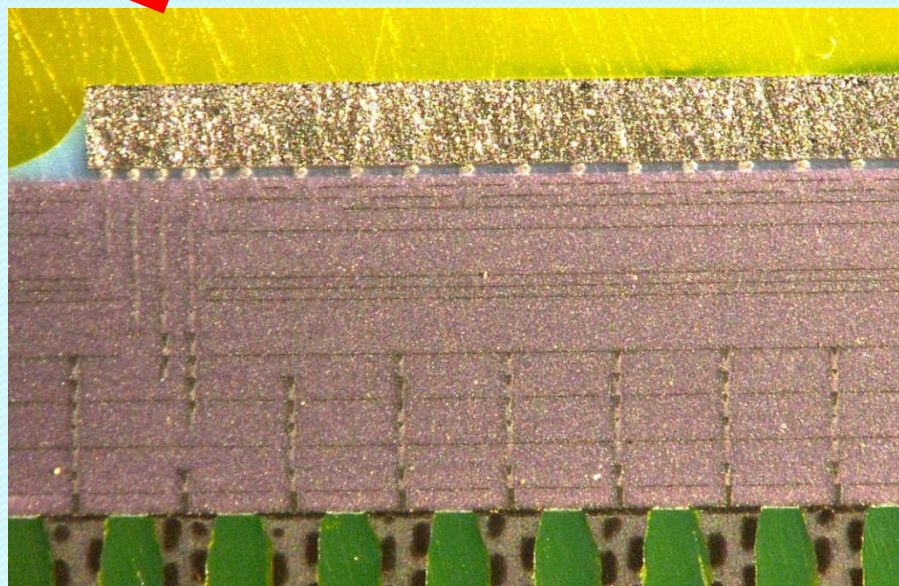
Substrate interface
230 MHz



X-Section FC-CGA



SN016 CGA 1517 I/O X-sectional Optical images





Summary - AE

- AE report is released: See <http://NEPP.nasa.gov>
- C-SAM for PEM
- C-SAM/X-ray of P-LGA assembly
- CGA/FC-CGA/FCBGA with heat sink
- FC-CGA, after heat sink sheared off
 - No C-SAM defect detection, 20 repeated with solder iron touches, a tip temp at 700°F
- FC-CGA with no heat sink
- Microsection to verify delamination
- C-SAM of fine pitch PBGAs
- **Recom:** Repeat with known defects



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Printed Electronics

Printed electronics technologies and **2D/3D** conventional/**rapid** printing of **organic**/non-organic electronic devices on various small/**large** substrates are projected to **grow exponentially** in commercial industry, providing an **opportunity** for various applications.

Additive manufacturing (**AM**) or 3D printing is a process for building up a three-dimensional solid object, **layer-by-layer**, from a 3D digital model. It is an additive process, contrary to traditional machining, which is a subtractive process.



Printed Electronics

Printed electronics technologies (**PET**) are emerging technologies that add significant **advantages** compared to the use of **costly** and **inflexible electronic** systems. These technologies can also be **edible, biocompatible, and conformable/stretchable**. For example on edibility, NASA recently (May 2013) awarded a contract to a company to make **food “on-demand”** from the ingredients; this allows for storage of ingredients rather than prepared food **meeting** the **demand** for **food** for long-distance travel such as humans to **Mars** by 2030. Other projects currently being pursued by NASA include **nanotechnology ink** and identifying ways PE technologies can be effectively implemented into various aspects of spacecraft. NASA is heavily involved in advancing the PET forward.



iNEMI Roadmap

- Paradigm Shifts
 - All PE to “hybrid” products
 - Cost per area rather than cost per function
 - No-traditional integration- Ubiquitous electronics
 - Scalable and high volume production
 - Novel form factor and low-cost electronics
- Enablers
 - Establish best-in-class manufacturing
 - Develop low temp interconnect materials
 - Improve materials/processes
 - Develop high performance/stable organic/inorganic/hybrid
 - Advance design and layout products



iNEMI Roadmap

Near-term opportunities are

- 1) Non-hybrid - an application that is comprised of only the emerging technology, or
- 2) **Hybrid** - an application that is manufactured using traditional electronics and devices, circuits, or components based on the new technology, e.g. a product with a printed display module and a silicon IC RF front-end.

For non-hybrid applications, one technical **barrier** concerns the development of in-line manufacturing **quality control** equipment. To benefit from the economies of scale that R2R and printing offers, systems must be developed and qualified for testing of the fabricated devices, circuits, and components.



Summary - PET

- PET report is released: See <http://NEPP.nasa.gov>
- PE market outpace Silicon Chip soon!
- Reviewed OE-A, ITRS, iNEMI roadmaps
 - Roadmaps continuously updated
- Review industry specifications
 - IPC, IEEE
- Presented hierarchy of device/package/systems
 - Reliability implication for each level
- Discussed briefly additive manufacturing
- OE-A stated “killer application” yet to be found!
- **Recom:** Build PCB/assembly for reliability



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Reference

<http://NEPP.nasa.gov>